Abstract of the Disclosure

A system and method are described for manufacturing a lapping plate. In one example, the lapping plate is made by covering a Tin-Antimony plate with photoresist and exposing the resulting photoresist layer with UV light through a wire mesh mask. After development, the non-etch areas can serve as land areas for diamond charging. Such a method may lead to fewer artifacts on the lapping plate and smaller diamond particle dimensions resulting in better processing of read/write heads, especially GMR heads.